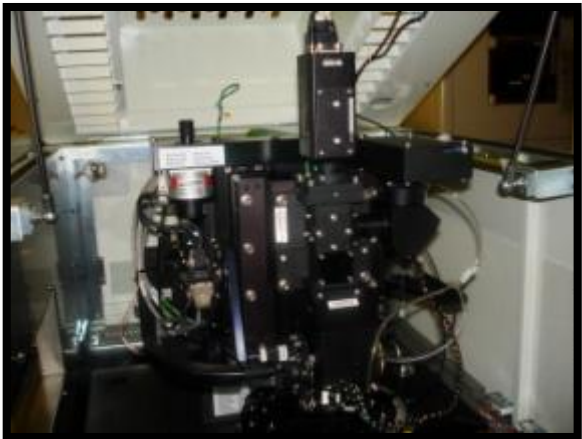


KLA TENCOR – ACHER10



Tool ID	M7POL401	OEM/Model	KLA TENCOR ACHER10
Serial Number	3116	Process	METROLOGY - OVERLAY
Vintage	January, 2004	Wafer Size	200 mm

- . Install Type: Stand-Alone
- . System sw version : 3.10.06sp6
- . Run daily pm Test : PZT P High voltage, PZT Z gain,PZT Z feedback
- . Halogen Light Source.
- . Replace Halogen lamp(HLS), P/N 127-483105-000
- . PDA Gain X,Y Axis
- . Wafer Surface focus and Analysis patened.
- . LINNIK camera uniformity , AMS camera uniformity
- . Check shutter response time.
- . Fringes ON to OFF mean time , Fringes OFF to ON mean time
- . GEM/SECS
- . Line Conditioner, 60Hz
- Power Requirements: V 208/230, 3-Phase/1-Phase, 50/60 Hz
- . RDM(Recipe database Manager) software of measurement recipes.
- . Archer Computer C.D Drive , KLASS Computer C Drive

1. Run daily PM Test

30Min

Back up Wafer Handler and Motion Parameter data.
C:\whbackup, C:\klamotion

2. Halogen Light Source.

30Min

Replace Halogen lamp(HLS), P/N 127-483105-000 (X)
Check Halogen Lamp Power supply output voltage. 9.862V

3.Noise Tests

AMS Camera Noise Level = 0.68 GL < 3.98

4. Light Map

30Min

50 BP (LINNIK) : Pass
12K BP (AMS 12K μ m FOV) : Pass

5. PDA

PDA Gain= 2527 GL
PDA X Axis centering Current Signal= 653
PDA Y Axis centering Current Signal= 648

EQUIPMENT DATASHEET

6. System.

30 Min

Check shutter response time.		
Fringes ON to OFF mean time= 65.3	msec.	20<x<80
Fringes OFF to ON mean time= 44.5	msec.	20<y<80

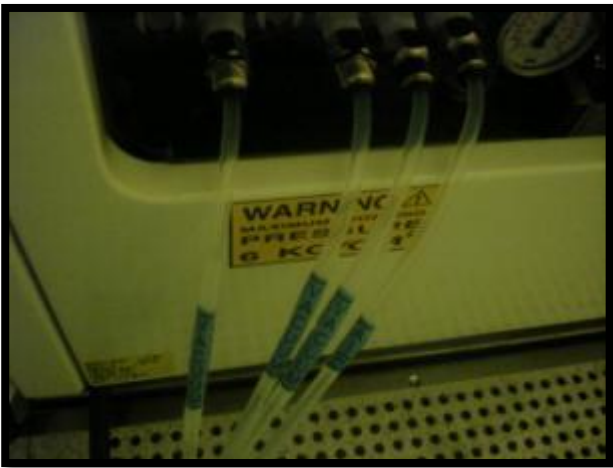
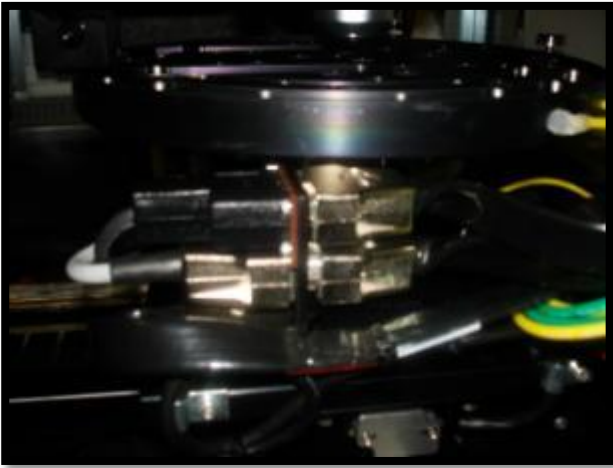
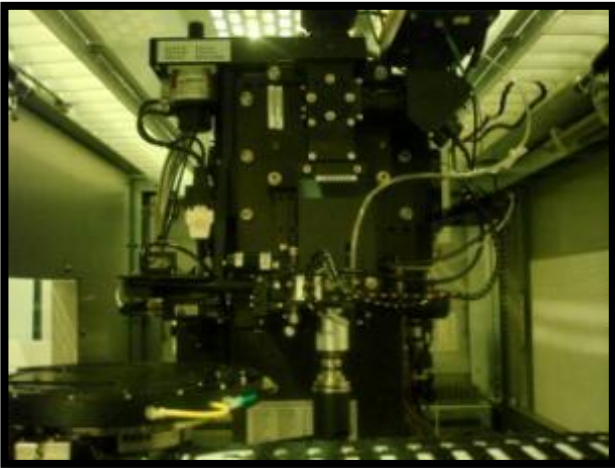
Check Translation Vector	
Coordinate X= 1848.9	µm
Coordinate Y= 61496.6	µm
Coordinate Z= 707.2	µm

7. Post check.

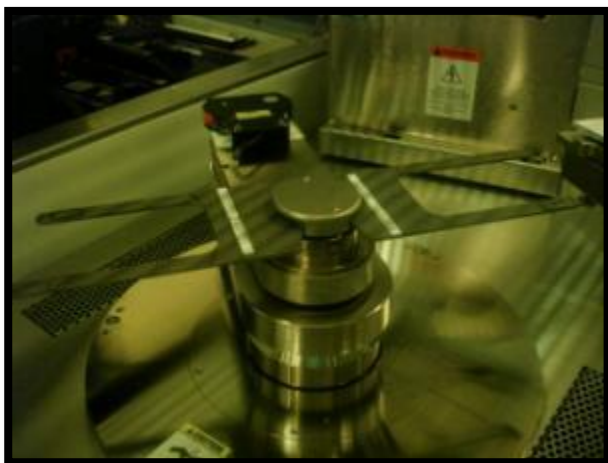
30Min

Backup the Wafer handler, Motion system, and floatation module parameters data.
Backup the Archer10 system data.
Run daily PM Set.

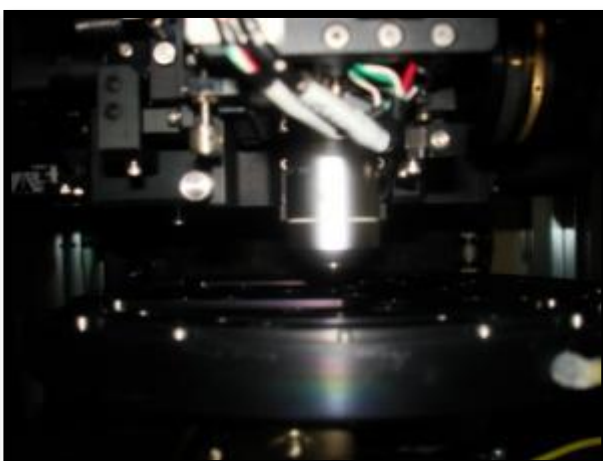
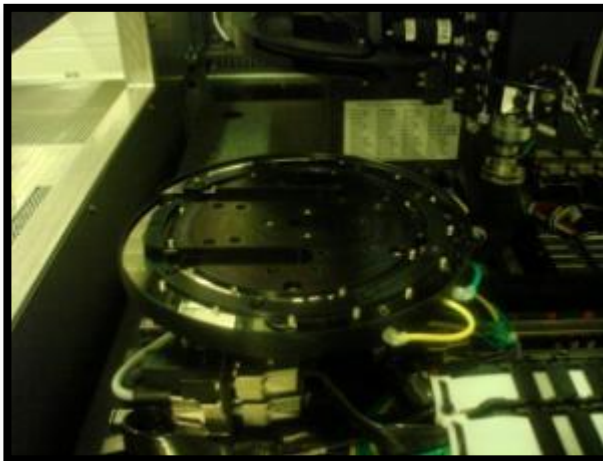
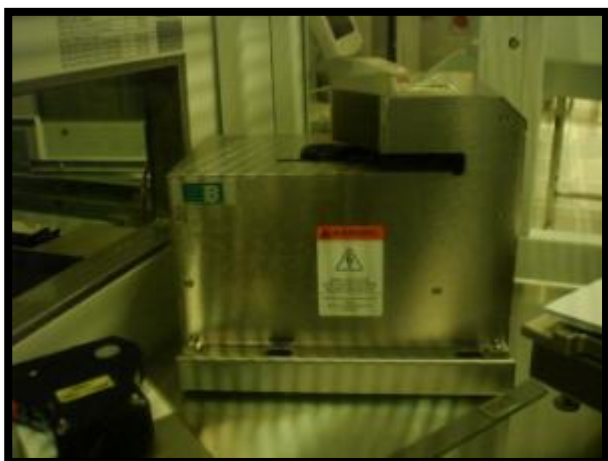
Duplicate Archer Computer C, D drive
Duplicate KLASS Computer C drive



EQUIPMENT DATASHEET



EQUIPMENT DATASHEET



EQUIPMENT DATASHEET

